Silicon tracking at CLIC, current overview and technology prospects

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CLIC environment

- **The CLIC environment has a great influence on the detector design** \Box Bunch trains consisting of 312 bunches (156 ns length) collide at 50 Hz, large period of inactivity
- - **Typically only 1 hard interaction per bunch train**
- **I** However...
	- \Box High bunch density leads to beam-beam interactions, producing $\mathrm{e}^+\mathrm{e}^{\textrm{-}}$ pairs and $\gamma\gamma$ => hadron backgrounds ■ Significantly lower radiation levels than for hadron colliders, no need to operate cold
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Overview of the tracking system

- CLIC detector is envisaged to contain all-silicon tracking detectors, with a vertexing detector and inner + outer trackers
	- \Box Pixellated vertex detector close to the interaction point, inner radius set by background levels
	- Large tracking volume with short strips/long pixels
- Some common requirements for all silicon detectors
	- Fine time-slicing of 10 ns to reduce beam-induced backgrounds
	- High granularity to keep occupancies below a few %
	- **E** Low material budget
- Overall size set by momentum resolution, with 4 T solenoid magnet

Vertex detector

- \blacksquare The vertex detector for CLIC has to be extremely low mass, 0.2 % X_0 per detection layer
	- Remove cooling pipes, replace with *forced air flow* => limit power consumption (power pulsing)
	- Arrangement of the detector into *double layers*, to allow sharing of support structure
- \blacksquare The current design has a radiation length of 0.4 % X_0 per double layer, with demanding performance requirements " A single hit resolution of ~3 μm, for transverse IP resolution 5 ⊕ 15/p[GeV] μm
- - Fast signal generation and time-stamping into 10 ns slices
	- \Box Low power consumption of 50 mW / cm²
- **EXP** Current technology baseline hybrid pixel detector
	- \Box Pixel size of 25 μ m \times 25 μ m
	- \Box ASIC thickness of 50 µm and sensor thickness of 50 µm

Vertex detector layout

- **I** Main steps have been to prove the air cooling option using realistic power consumption numbers
	- Finite element calculations of the proposed layout
	- Thermal mockup constructed to demonstrate cooling and compare to simulation (similar to STAR)
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Tracker

- **Large tracking volume proposed: area of silicon ~100 m², outer radius 1.5 metres, barrel length 2.5 metres entity of the USD metres**
- **I** Material budget for the tracker is 1-2 $\%$ X_0 per layer
	- \Box Air cooling not feasible in such a large volume \Rightarrow water cooling
	- Power budget of 100-150 mW / cm²
	- Momentum resolution of σ_{P} / p_T² ~ 2 × 10⁻⁵ GeV⁻¹
	- \Box Single hit resolution of 7 μ m in the bending plane
- **E** Current technology baseline **monolithic CMOS**
	- \Box Long pixels with maximum size of 30 μ m \times (1-10) mm
	- Sensor thickness of 200 μm

Tracker layout

- \blacksquare In a similar vein to the vertex detector, proof of concept prototyping to confirm material budget assumptions □ Construction of a section of the barrel region, to compare finite element calculations with measurements
□ Cennesting necles developed and febricated .eff the shelf serben fibre tubes connecting ■ Connecting nodes developed and fabricated, off-the-shelf carbon fibre tubes connecting **Executed Stiffmace** achieve
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	- \Box Stiffness achieved with low mass structure, total weight 926 g (70 % tubes, 26 % nodes, 4 % glue)
- **Simulation results for deformations give acceptable performance with total** mass of the support structure of 0.125% X_0

- \blacksquare In the last (~5) years many novel detectors have been designed taking advantage of recent commercially available CMOS processes
	- Plethora of new devices, many with only subtle differences, processes typically differ by Foundry and technology size…
- CLIC has been heavily involved in several of these areas, which are also of interest for high luminosity LHC upgrades, as well as more broadly to HEP and medical imaging

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Emerging silicon technologies

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Emerging silicon technologies

E Conventional hybrid pixel detector

- \Box Sensor (high resistivity) typically consists of a pn diode, which acts as the charge collection node
- \Box Readout chip (low resistivity) connected via small solder bumps, typically ~15 µm diameter
- Widely used in particle physics (CMS, ATLAS, ALICE, LHCb VELO upgrade...)
- \Box Small cell sizes $\mathcal{O}(50 250 \text{ }\mu\text{m})$
- **Extensive functionality on-pixel**
- ! But…
	- **Bump bonding still costly**
	- Limit on device thickness for stability
	- **E** Currently limiting on pixel pitch

Emerging silicon technologies

- **IDED** Monolithic Active Pixel Sensors electronics and sensor are both deposited on silicon wafers, why not do both? \Box Integrated sensor + readout => lower mass, no bump-bonding
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	- Widely used in digital cameras (check your smartphone!)
- What's the catch?
	- \Box Electronics consist of n-wells and p-wells \Rightarrow competition for charge collection
	- " Typically low on-pixel functionality
	- Limited depleted region, charge collected mostly by diffusion (slow)

Emerging silicon technologies

- **I** What can we do better?
	- Shield electronics in order to prevent charge being collected where you don't want it
- But…
	- Charge collection still by diffusion

Emerging silicon technologies - High Resistivity (HR) CMOSCERN

- **I** What can we do better?
	- Shield electronics in order to prevent charge being collected where you don't want it
	- Extend depletion region: use a high resistivity substrate to extend built-in depletion

(~100 V) to be applied to the substrate

Emerging silicon technologies - High Voltage (HV) CMOS

- **I** What can we do better?
	- Shield electronics in order to prevent charge being collected where you don't want it

■ Extend depletion region: apply a bias voltage

 \Box Need to shield electronics from high electric field \Rightarrow move inside the collection diode. Allows a high voltage

Emerging silicon technologies - Silicon on Insulator (SOI)

- **E** Another approach to isolate the electronics and collection diode
	- \Box Readout electronics don't need much space why not just separate two regions of the silicon?
- **Example 20 Silicon oxide can be used as an insulation layer to prevent interference between the sensor and electronics**
	- Full CMOS on the upper silicon layer, conventional planar silicon sensor underneath
	- Connection through **vias** in the oxide layer

Emerging silicon technologies

- **E** Conventional hybrid pixel detectors still have advantages
	- Technology size can be much smaller (cf. 65 nm) than those available in integrated technologies (HR- or HV-CMOS)
	- \Box Integrated devices still suffer from noise injected into the sensing diode limit to on-pixel functionality possible

Emerging silicon technologies - CCPD

E. Another solution available: capacitive coupling of the sensor to the readout

- Given small pixel capacitance only a viable option if amplification implemented on the sensor => requires integrated technology (HR- or HV-CMOS)
- Avoids bump-bonding, devices are simply glued together

En Capacitively Coupled Pixel Detectors

High Voltage

- **Perototype readout chip for the CLIC vertex detector, for capacitively coupled** HV-CMOS sensors and thin (50 μm) planar sensors
	- □ One of the first readout chips for HEP designed and produced in 65 nm
	- Providing feedback for high-luminosity LHC projects, RD53
- **E** Chip is an evolution of the Medipix/Timepix family of ASICs, with similar design
	- \Box Amplifier + discriminator on each pixel, 25 μ m \times 25 μ m pixels
	- \Box In-pixel measurement of both charge and particle arrival time
	- \Box Shuttered readout with power pulsing of the pixel matrix, to match the CLIC beam structure

Many results produced with the current chip, improved design has recently been fabricated (results expected soon!)

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CLICpix

HV-CMOS sensors

- In-depth studies of HV-CMOS devices have been carried out for CLIC, with knock-on contributions to high-luminosity LHC (ATLAS upgrade)
	- Proof-of-concept results on capacitively coupled pixel detectors showed high detection efficiency and reliable operation
	- Detailed fabrication studies carried out, for extrapolation to detector-scale production

- CLICpix+CCPDv3 assemblies were produced and wire bonded to printed circuit boards (PCBs). The ■ Common chip development with ATLAS the glue on top of one the chips and bringing them together with a controlled force (up to 100 kg) and
	- $m!$ applied the first $UVCMOC$ chine doveloped for □ CCPD family, one of the first HV-CMOS chips developed for HEP
	- C produced in collaboration with the Medipix grou and constant over the pixel matrix. Figure 7 shows a cross section picture of one of the assemblies. The \Box New ASIC produced in collaboration with the Medipix group -C3PD

- Existing devices fabricated with HR-CMOS used as a test-bed for several experiments (ALICE, ATLAS upgrade)
	- \Box Prototype chip does not yet contain full readout electronics in-pixel amplifier is read out by an external ADC
	- Extensive measurement in lab and beam tests, backed up by simulation
	- \Box Promising results have led to consideration of the technology for the CLIC tracker
	- \Box Full chip layout with integrated readout being developed in collaboration with the Medipix group and ALICE

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HR-CMOS

SOI

- **I** SOI development ongoing in several groups worldwide
	- \Box Assemblies have been produced to test several architectures (CLIC + more general HEP)
	- Different readout schemes, methods of in-pixel signal processing
	- Samples studied in testbeam at the SPS, analysis ongoing
	- **Promising results, chips fully functional and good single hit resolution measured**
	- Double SOI process also considered, for improved radiation tolerance

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Buried oxide

2nd Buried oxide

Simulations - TCAD

- **IDURE Understanding of lab and beam measurements aided massively by TCAD finite element simulations**
	- \Box Ability to disentangle intrinsic sensor performance and electronics effects
	- Leakage current and breakdown points predicted well for implemented pixel geometry
	- □ Observed charge collection in HV-CMOS devices only accounted for with avalanche/charge multiplication models
- - □ Optimisation of the chip layout to improve breakdown characteristics
	- \Box Additional submissions with higher resistivity substrates

Simulations - Geant4

- **ID In addition to TCAD, full Geant4-based simulations of detectors and set-ups have been** developed as part of the CLICdp project
	- □ Contributions to open-source software suite **Allpix**, in use in several collaborations both inside and outside HEP
	- Provides a simple interface to produce commonly used detector geometries
	- Detailed simulation of electric field and magnetic field effects, charge carrier propagation
	- \Box Currently being upgraded: watch out for allpix²

Entries
external RMS: 14.39 ± 0.06 Data
RMS: 14.34 ± 0.03 0.02 0.01 -0.04 -0.02 0.02

Future work

- **I** Where are we now in terms of silicon?
	- Low material Fast timingSingle hit resolution **NUMBER OF A STRAIGHTEN**
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	-
- \Box Each of the requirements are achievable individually, trick is to reach all at once! □ CLICpix with either HV-CMOS or planar silicon sensor getting close to vertex requirements \Box Dedicated monolithic chip for the tracker to be produced in the near future ■ CLIC silicon R&D touches on many areas, helping to push new technologies **D** Overlap with HL-LHC detector upgrades ■ Keep a close eye on developments in CMOS processing for the future
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Future work

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